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Title: APPARATUS AND METHOD FOR CONTROLLING FILM THICKNESS
IN A CHEMICAL MECHANICAL PLANARIZATION SYSTEM

Inventor: Y. Gotkis

App. No. 10/674,373

Docket No: LAM2P445

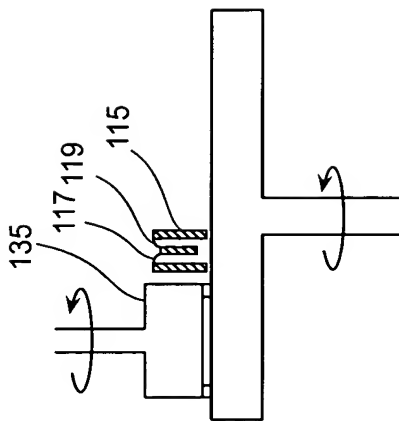


FIG. 5A

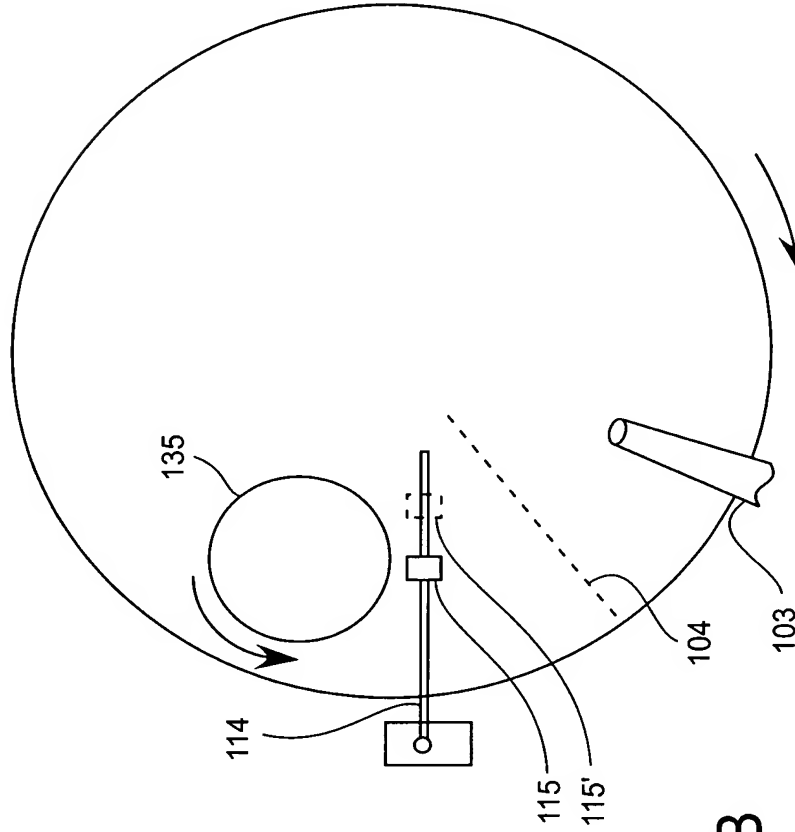


FIG. 5B

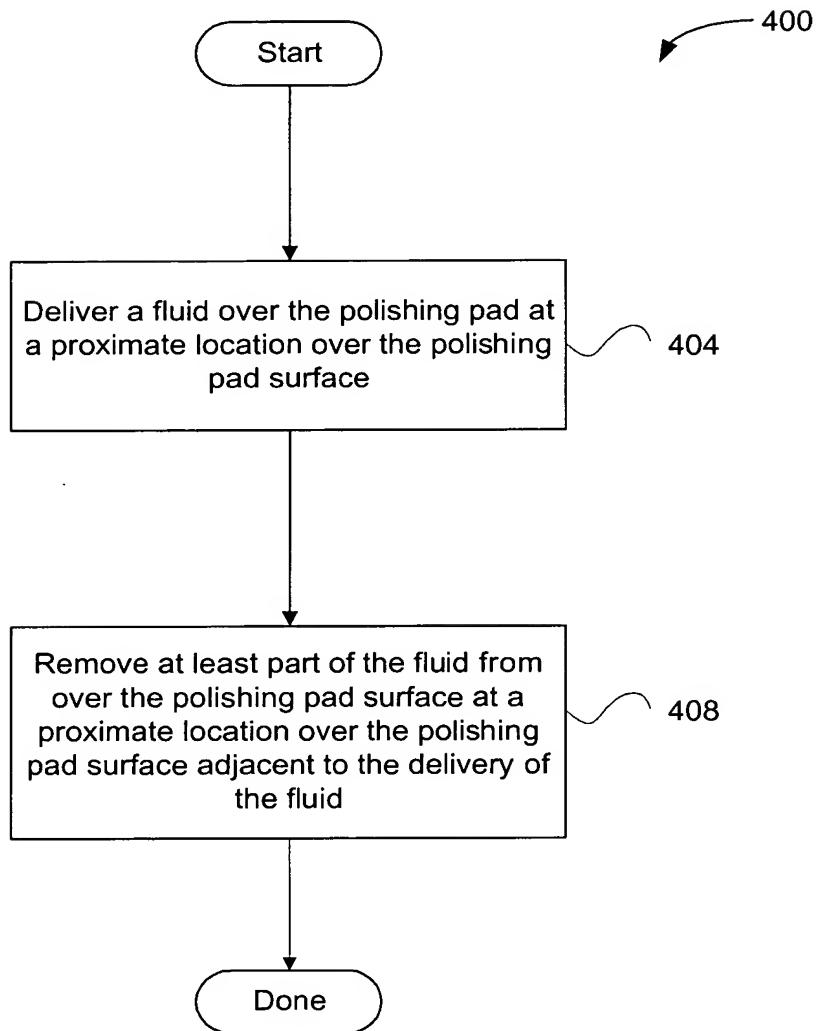


FIG. 6

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